

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: JASPER et al.

New U.S. Patent Application No.

Filed: HEREWITH

Title: OFF-AXIS LEVELLING IN  
LITHOGRAPHIC PROJECTION  
APPARATUS

Group: Unassigned

Examiner: Unassigned

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March 6, 2000

PRELIMINARY AMENDMENT

Hon. Commissioner of Patents and Trademarks  
Washington, D. C. 20231

Sir:

Prior to fee determination and initial review of the above-identified application,  
kindly amend as follows:

**IN THE SPECIFICATION:**

Page 1, prior to line 3, insert --BACKGROUND OF THE INVENTION-- (centered);

prior to line 18, insert --SUMMARY OF THE INVENTION-- (centered);

line 20, delete "system" and replace with --systems--.

Page 2, line 5, delete "in one go" and replace with --at once--;

line 29, delete "position" and replace with --positions--.

Page 5, line 9, delete "metallisation" and replace with --metallization--.

Page 6, line 6, insert --BRIEF DESCRIPTION OF THE DRAWINGS-- (centered).

Page 7, line 15, insert --DETAILED DESCRIPTION OF THE PREFERRED

EMBODIMENTS-- (centered).

Page 9, line 12, delete "in one go" and replace with --at once--.